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Oliver Fänhle**
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Contents

v	<i>Authors</i>
vii	<i>Conference Committee</i>
ix	<i>Introduction</i>

FIFTH EUROPEAN SEMINAR ON PRECISION OPTICS MANUFACTURING

10829 02	Testing high accuracy optics using the phase shifting point diffraction interferometer [10829-3]
10829 03	Simulation of MSF errors using Fourier transform [10829-4]
10829 04	First steps in ELT optics polishing [10829-5]
10829 05	Characterizing the resolving power of laser Fizeau interferometers [10829-6]
10829 06	ABC-polishing [10829-8]
10829 07	Basics of ion beam figuring and challenges for real optics treatment [10829-9]
10829 08	Tilted wave interferometry for testing large surfaces [10829-10]
10829 09	Filled-Up-Microscopy (FUM): a non-destructive method for approximating the depth of sub-surface damage on ground surfaces [10829-11]
10829 0A	Workpiece self-weight in precision optics manufacturing: compensation of workpiece deformations by a fluid bearing [10829-12]
10829 0B	Fast and reliable in-situ measurements of large and complex surfaces using a novel deflectometric device [10829-16]
10829 0C	Spectrally controlled source for interferometric measurements of multiple surface cavities [10829-19]
10829 0D	Mid-spatial frequency errors of mass-produced aspheres [10829-20]
10829 0E	Tight tolerances for large-volume precision-pressed plastic optics (COMPAS) [10829-21]
10829 0F	On the metrology of the MSF errors [10829-22]

- 10829 OG **Efficient assembly of lens objectives using sub-cell alignment turning** [10829-25]
- 10829 OH **gPVA: a system for the classification of grinding tools** [10829-26]
- 10829 OI **DefGO** [10829-28]
- 10829 OJ **Increasing critical depth of cut in ductile mode machining of tungsten carbide by process parameter controlling** [10829-30]
- 10829 OK **SPDT and standard CNC-grinding of tungsten carbide molds for precision glass molding: an experimental process analysis** [10829-31]
- 10829 OL **Contribution of the phase transfer function of extended measurement cavities to mid spatial frequencies and the overall error budget** [10829-32]
- 10829 OM **Closed-loop next generation laser polishing** [10829-34]